

FACSIMILE COVER SHEET**TO: Examiner Ginette Peralta**Company: Assistant Commissioner for Patents
Fax No.: 703/872-9318**FROM: Julie G. Cope, Reg. No. 48,624/amm**

Date: March 21, 2003

Pages: 9

(including cover page)

Our Docket No.: MIO 0024 PA

Transmission No.: _____

Patents, Trademarks and Related Matters

Killworth, Gottman, Hagan & Schaeff, L.L.P.

One Dayton Centre
One South Main Street, Suite 500
Dayton, Ohio 45402-2023937.223.2050
Fax | 937.223.0724
E-mail | kghs@kghs.com
www.KGHS.com**FAX RECEIVED**

MAR 21 2003

TECHNOLOGY CENTER 2800

- | |
|--|
| <input checked="" type="checkbox"/> ORIGINAL WILL NOT FOLLOW |
| <input type="checkbox"/> ORIGINAL WILL FOLLOW BY: |
| <input type="checkbox"/> REGULAR MAIL |
| <input type="checkbox"/> EXPRESS MAIL |

Remarks:

U.S. Patent Application Serial No. 08/915,658**OFFICIAL****OFFICIAL****OFFICIAL****CONFIDENTIAL FACSIMILE COMMUNICATIONS**

The information contained in this facsimile message, and any and all accompanying documents, constitutes confidential information which is the property of Killworth, Gottman, Hagan & Schaeff. If you are not the intended recipient of this information, any disclosure, copying, distribution, or taking of any action in reliance on this information, is strictly prohibited. If you have received this facsimile message in error, please notify us immediately to make arrangements for its return to us. Thank you.

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of

Applicant : Jigish D. Trivedi
 Serial No. : 08/915,658
 Filed : August 21, 1997
 Title : LOW RESISTANCE METAL SILICIDE LOCAL INTERCONNECTS
 AND METHOD OF MAKING
 Docket : MIO 0024 PA
 Examiner : G. Peralta
 Art Unit : 2814

CERTIFICATE OF FACSIMILE TRANSMISSION
 I hereby certify that this paper is being facsimile transmitted to the Patent and Trademark Office (Fax No. 703/872-9318) on March 21, 2003.

Julie G. Cope
 Julie G. Cope Reg. No. 48,624

FAX RECEIVED

Assistant Commissioner for Patents
 Washington, D.C. 20231

MAR 21 2003

TECHNOLOGY CENTER 2800

AMENDMENT

APR 1 2003 08:00 PM PALKER
 DSASFAI 00000006 09915658
 01 FC:1202
 01 FC:1201
 This amendment is being filed in response to the office action mailed on January 2, 2003. Reconsideration is respectfully requested in light of the amendments and remarks below.

CLEAN VERSION OF THE AMENDMENTS

A version of the amendments showing the markings is provided in a separate appendix attached to this paper.

31. (Amended) A local interconnect comprising:

a composite structure comprising a first metal silicide, a second metal silicide and an intermetallic compound separating said first metal silicide from said second metal silicide, wherein said intermetallic compound comprises metal from said first metal silicide and metal from said second metal silicide, wherein said intermetallic compound contains no non-metallic materials.

35. (Amended) A local interconnect for connecting a first active semiconductor region to a second active semiconductor region on a substrate assembly, said first and second active semiconductor regions being separated by an insulating region, said local interconnect comprising:

03 PALKER 00000001 08915658

18.00 OP
 84.00 OP

01 FC:1202
 01 FC:1201

Serial No. 08/915,658

Atty. Docket No. MIO 0024 PA

12
ent

a composite structure comprising a first refractory metal silicide, a second refractory metal silicide and an intermetallic compound separating said first refractory metal silicide from said second refractory metal silicide, wherein said intermetallic compound comprises refractory metal from said first refractory metal silicide and refractory metal from said second refractory metal silicide, said refractory metal from said first refractory metal silicide being different from said refractory metal from said second refractory metal silicide, wherein said intermetallic compound contains no non-metallic materials.

37. (Amended) A semiconductor device comprising:

63
cont

- a substrate assembly having at least one semiconductor layer;
- at least one field effect transistor formed in said at least one semiconductor layer, said at least one field effect transistor having a source, a drain and a gate; and
- a local interconnect for connecting at least one of said source, said drain and said gate to another active area within said substrate assembly, said local interconnect comprising a composite structure comprising a first refractory metal silicide, a second refractory metal silicide and an intermetallic compound separating said first refractory metal silicide from said second refractory metal silicide, wherein said intermetallic compound comprises refractory metal from said first refractory metal silicide and refractory metal from said second refractory metal silicide, wherein said intermetallic compound contains no non-metallic materials.

38. (Amended) A memory array comprising:

- a plurality of memory cells arranged in rows and columns and formed on a substrate assembly having at least one semiconductor layer, each of said plurality of memory cells comprising at least one field effect transistor; and
- at least one local interconnect for connecting at least one of a source, a drain and a gate of said at least one field effect transistor in one of said plurality of memory cells to one of an active area within said one memory cell or to one of a source, a drain and a gate of said at least one field effect transistor in another one of said plurality of memory cells, said local interconnect comprising a composite structure comprising a first refractory